



IPW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki SATO

Group Art Unit: 1792

Application No.: 10/594,458

Examiner: L. VINH

Filed: September 26, 2006

Docket No.: 129546

For: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the March 11, 2009 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**